

# Vacuum and mechanical design of ILC DR

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## Integration design: usual consideration

| field                               | parameter  | implication  |
|-------------------------------------|--|--|
| Beam dynamics                       | Beam aperture<br>Impedance/wake field<br>BPM                               | Vacuum chamber aperture,<br>Shape, material, coatings<br>BPM design            |
| SR power                            | Power, photon reflectivity   | SR power absorber design,<br>cooling   |
| Vacuum design                       | SR induced gas desorption  | Pumping scheme, vacuum<br>chamber material, coatings                           |
| Fast ions<br>(in e <sup>-</sup> DR) | Gas density specification<br>Ion collection                                | UHV pumping scheme<br>Mechanical design  |
| Mechanical solutions                | Mechanical design,<br>component integration,<br>mechanical stability, etc. | Shape, material, supports,<br>cooling, welding, brazing,<br>feedthroughs, etc. |
| Cost                                | Cost optimisation  | All systems  |

## Integration design: specific problems in e<sup>+</sup> rings

| field                            | parameter  | implication  |
|----------------------------------|--|--|
| Ion induced pressure instability | Rapid gas density grow<br>Residual gas ionisation<br>Ion energy, ISD yield | Vacuum design: Requires greater pumping speed and low outgassing walls |
| E-cloud mitigation               | PEY (minimising a number of photoelectrons in beam pipe)                   | Shape, antechamber, SR absorbers, coatings, low photon reflectivity    |
|                                  | SEY (minimising)   | Wall material, Coating, Grooves, electrodes                            |
|                                  | Residual gas ionisation  | UHV pumping scheme   |
|                                  | Electron simulated gas desorption  | Low outgassing walls   |
| Mechanical solutions             |  | More complicate integration  |
| Cost                             | Guaranteed performance at the lowest cost                                  | Challenging  |

## Vacuum required for ILC DRs

- The need to avoid the fast ion instability leads to very demanding specifications for the vacuum in **the electron damping ring** [Lanfa Wang, private communication]:
  - $< 0.5$  nTorr CO in the arc cell,
  - $< 2$  nTorr CO in the wiggler cell and
  - $< 0.1$  nTorr CO in the straight section
- In **the positron damping ring** required vacuum level was not specified and assumed as **1 nTorr** (common figure for storage rings)

## Ideal vacuum chamber for vacuum design

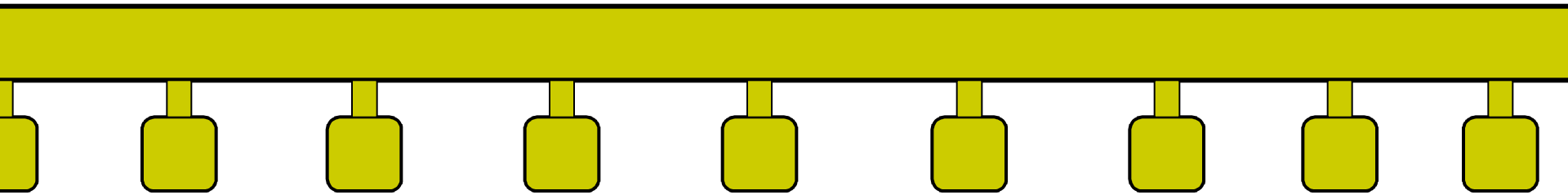
for the electron ring and, where possible, for the positron ring:

- Round or elliptical tube
  - Cheapest from technological point of view
- No antechamber if SR power can be absorbed with vacuum chamber wall cooling
  - Beam conditioning is most efficient
  - Easy geometry for NEG coating
- NEG coated
  - Requires less number of pumps with less pumping speed
  - 160°C for NEG coating activation instead of 220-300°C bakeout
  - Choice of vacuum chamber material (stainless steel, copper and aluminium) does not affect vacuum in this case
  - Residual gas CH<sub>4</sub> and H<sub>2</sub> (almost no CO and CO<sub>2</sub>)

## Pumping scheme along the ILC DR arc

An aluminium tube after bakeout at  $220^{\circ}\text{C}$  for 24 hrs and 100 Ahr beam conditioning:

- a pump with  $S_{\text{eff}} = 200$  l/s every 5 m
- $\text{H}_2$ , CO and  $\text{CO}_2$



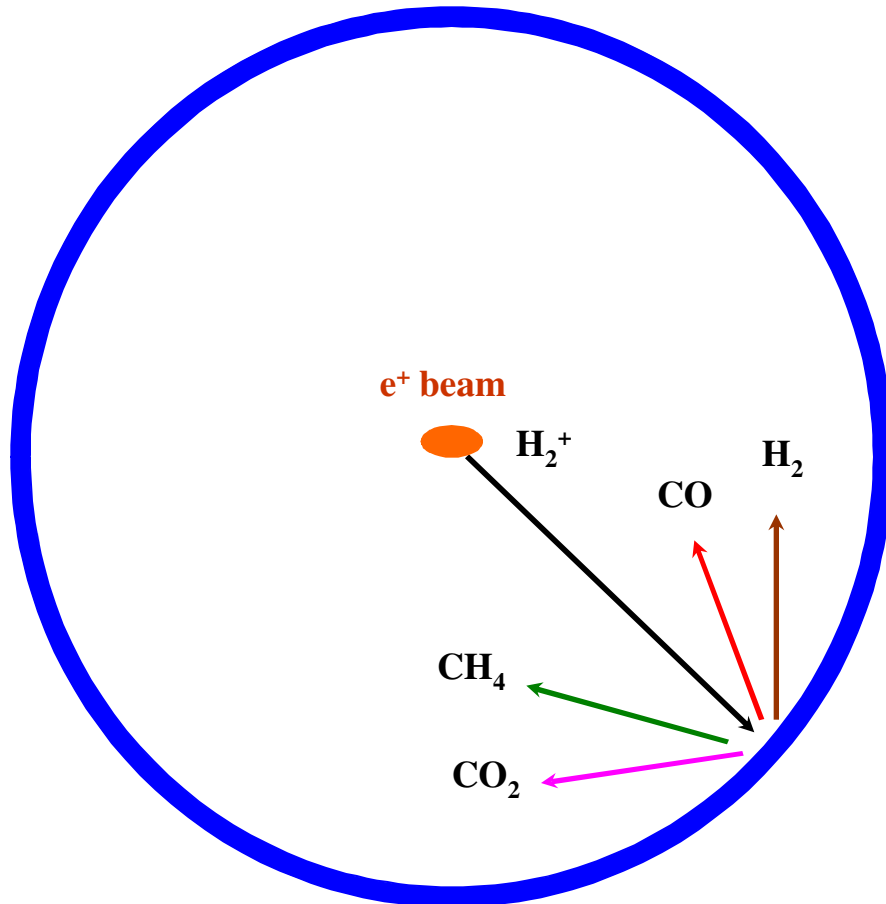
Inside a NEG coated tube after activation at  $160^{\circ}\text{C}$  for 24 hrs and 100 Ahr beam conditioning: a pump with  $S_{\text{eff}} = 20$  l/s every 30 m

- $\text{H}_2$  and  $\text{CH}_4$



*O. Malyshev. Vacuum Systems for the ILC Damping Rings. EUROTeV Report-2006-094.*

# Ion induced pressure instability in ILC positron DR



$$P = \frac{Q}{S_{eff} - \chi \frac{\sigma I}{e}}$$

where

$Q$  = gas desorption,

$S_{eff}$  = effective pumping speed,

$\chi$  = ion induced desorption yield

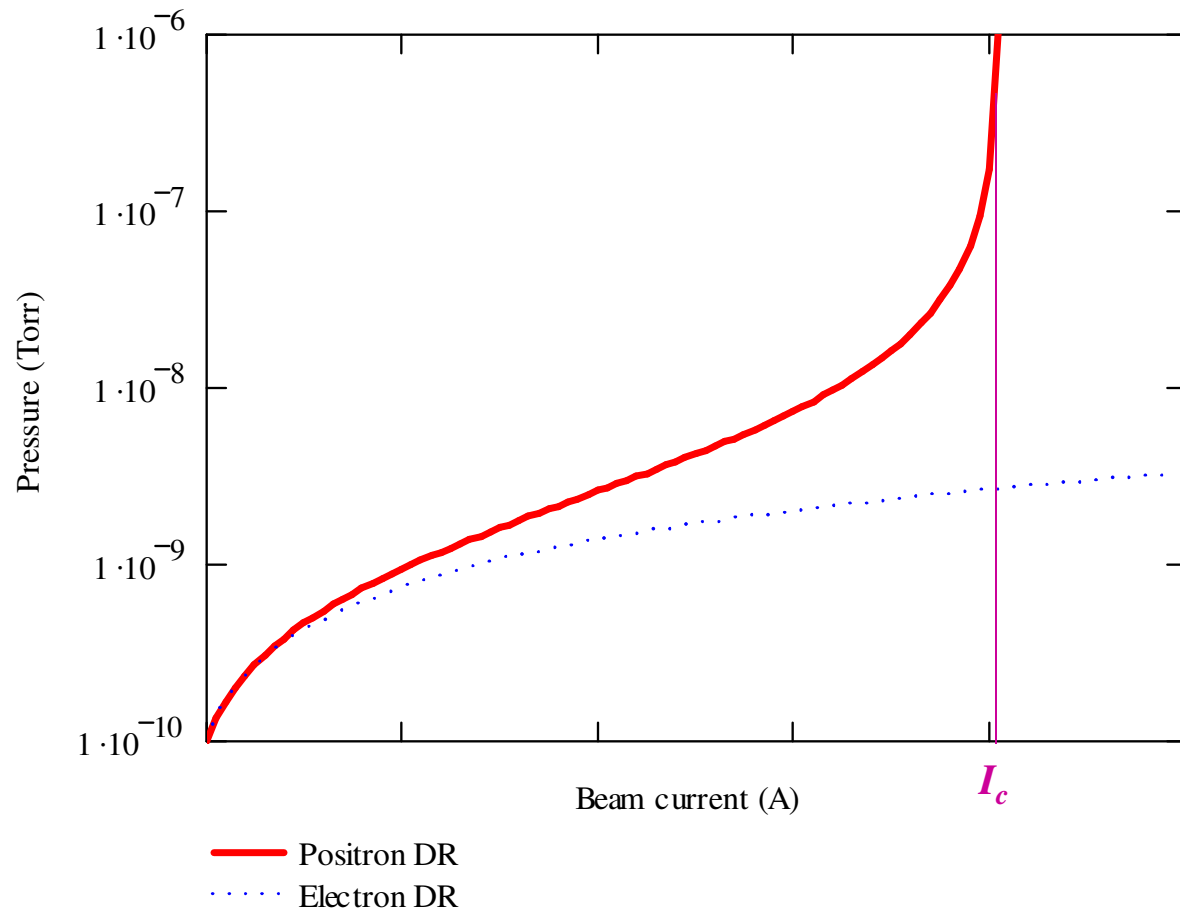
$\sigma$  = ionisation cross section,

$I$  = beam current.

$$\chi = f(E_{ion}, M_{ion}, material, bakeout, \dots)$$

$$E_{ion} = f(N_{bunch}, \tau, T, \sigma_x, \sigma_y, \dots)$$

# Critical current



Critical current,  $I_c$ , is a current when pressure (or gas density) increases dramatically.

Mathematically, if

$$P = \frac{Q}{S_{eff} - \chi \frac{\sigma I}{e}}$$

$$\text{when } S_{eff} > \chi \frac{\sigma I}{e}$$

Hence  $I < I_c$ ,

$$\text{where } I_c = \frac{S_{eff} e}{\chi \sigma I}$$



## The ion stability for different vacuum chamber materials, $I_{\max}=0.4 \text{ A}$

| Vacuum chamber   | $I_c$ (A) | $I_c / I_{\max}$ | Domin. gas      | Stable or not |
|--|-----------|------------------|-----------------|---------------|
| <b>Distance between pumps <math>L = 6 \text{ m}</math>, <math>ID = 50 \text{ mm}</math></b>  |           |                  |                 |               |
| 316LN  | 1.0       | 2.5              | CO              | Yes           |
| Pure Al  | 0.5       | 1.25             | CO              | No            |
| Ti alloy   | 1.1       | 2.8              | CO              | Yes           |
| <b>Distance between pumps <math>L = 6 \text{ m}</math>, <math>ID = 60 \text{ mm}</math></b>  |           |                  |                 |               |
| 316LN  | 1.24      | 3.1              | CO              | Yes           |
| Pure Al  | 0.64      | 1.6              | CO              | No            |
| Ti alloy   | 1.4       | 3.5              | CO              | Yes           |
| <b>Distance between pumps <math>L = 10 \text{ m}</math>, <math>ID = 50 \text{ mm}</math></b> |           |                  |                 |               |
| 316LN  | 0.47      | 1.2              | CO              | No            |
| Pure Al  | 0.24      | 0.6              | CO              | No            |
| Ti alloy   | 0.53      | 1.3              | CO              | No            |
| <b>Distance between pumps <math>L = 40 \text{ m}</math>, <math>ID = 50 \text{ mm}</math></b> |           |                  |                 |               |
| NEG coated   | 5         | 12.5             | CH <sub>4</sub> | Yes           |

## Pressure instability conclusions:

- Ion energy =  $\sim 300$  eV, but could be larger for a smaller beam
- For given parameters and large uncertainties, there is a possibility of ion induced pressure increase and even ion induced pressure instability in positron damping ring if pumping is insufficient.
- **Use of NEG coating fully eliminates the probability of the ion induced pressure instability.**

***O.B. Malyshev. Study of Ion Induced Pressure Instability in the ILC Positron Damping ring. EUROTeV Report-2008-058.***

# Electron cloud

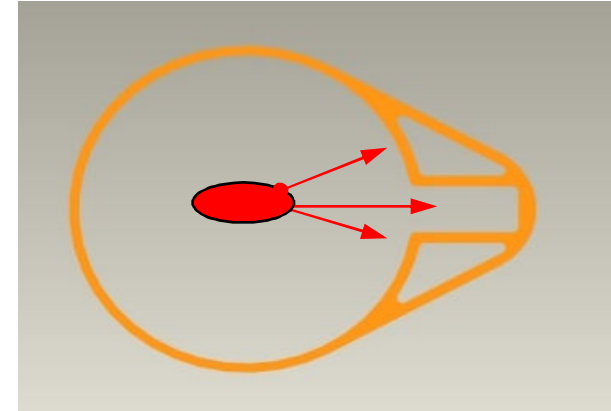
- Three sources of electrons:
  - Photoelectrons
  - Secondary electrons
  - Gas ionisation

# Photoelectrons

- Photoelectrons:

$PEY = \kappa F \Gamma R$ , where  $\Gamma$  is a total SR flux.

- A photon flux absorbed in beam chamber can be minimised with an antechamber,  $F$  is an antechamber efficiency
- Lower photon reflectivity,  $R$ , helps as well
- Choice of material, surface treatment, conditioning, coating (ex.: **TiZrV**) allows to reduce photo-electron emission yield,  $\kappa$



***O.B. Malyshev and W. Bruns. ILC DR vacuum design and e-cloud. Proc. of EPAC08, p.673, and references with in the paper.***

# PEY for different types of vacuum chamber

| Beam pipe  | Inside magnets, $B \neq 0$   |  | Downstream straights near the magnet, $B = 0$ |          |                  |
|--|------------------------------|--|---|----------|------------------|
|  | Tube                         | Antechamber  | Tube  | Solenoid | Antechamber      |
| <b>Estimated achievable PEY</b>                    |                              |  |   |          |                  |
| Dipole SR  | $3 \cdot 10^{-4}$ –<br>0.065 | <b><math>3 \cdot 10^{-6}</math></b> –<br>$6.5 \cdot 10^{-3}$ | 0.01–0.1                                      | 0.01–0.1 | $10^{-4}$ – 0.01 |
| Wiggler SR   | $3 \cdot 10^{-3}$ –<br>0.65  | <b><math>3 \cdot 10^{-5}</math></b> –<br>$6.5 \cdot 10^{-2}$ | 0.1–1   | 0.1–1    | $10^{-3}$ – 0.1  |
| <b>Required maximum PEY from e-cloud modelling</b> |                              |  |   |          |                  |
| Dipole   | $\sim 10^{-4}$               |  | ?   |          |                  |
| Wiggler  | $\sim 10^{-4}$               |  | ?   |          |                  |

## Secondary electrons

- Secondary electron yields, e-cloud and mitigation techniques are intensively studied in many places, see all other talks on this session.
- Secondary electron
  - Choice of material (intrinsic SEY for flat and dense surface)
  - Surface treatment to modify surface micro-structure (air bake, anodisation, ion bombardment, etc.)
  - Low SEY coatings: material *and* its surface micro-structure: **TiZrV or TiN or Amorphous C coatings**
  - Geometrical electron traps (ex.: grooves)
  - Field suppression:
    - Magnetic material coatings
    - Biased electrodes
    - Solenoid field

# Gas ionisation

- Ionisation cross section of heavy molecules is higher:
  - $\sigma(\text{CO}_2) = 12 \sigma(\text{H}_2)$
- Ionisation in ILC DR can be neglected when CO pressure is below  $10^{-8}$  Torr
  - Surface treatment and conditioning
  - Low outgassing coating (ex.: **TiZrV** coating)
  - Better pumping (ex.: **TiZrV** coating or more pumps)

***O.B. Malyshev and W. Bruns. ILC DR vacuum design and e-cloud.  
Proc. of EPAC08, p.673.***

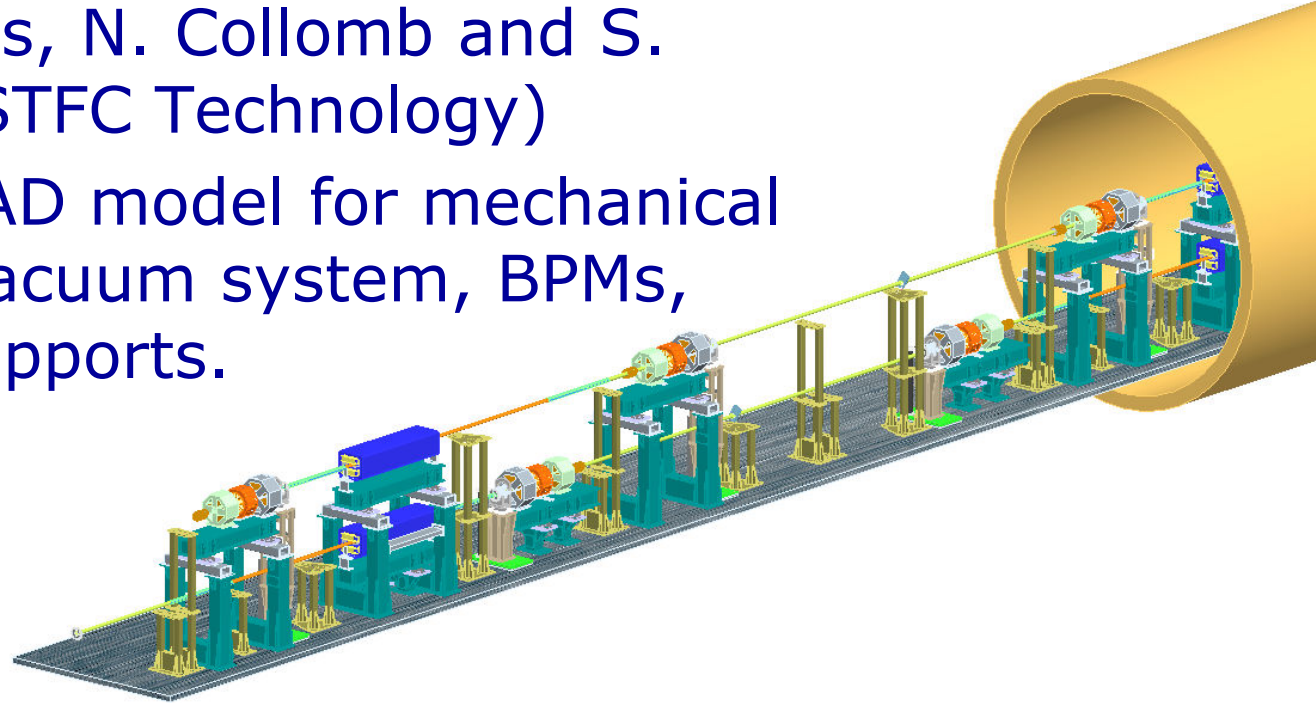
## Selecting an e-cloud mitigation

- A complex solution required:
  - Good solution against Photo-electrons or Secondary electrons might lead to higher gas density and higher gas ionisation, and vice versa, best pumping solution might compromise PEY and SEY mitigation.
  - NEG coating is the best choice for UHV systems.
  - NEG coating + grooves might be sufficient in many places
  - Using other coatings and other mitigation techniques increases a cost of DR and should be only used where it is essential.



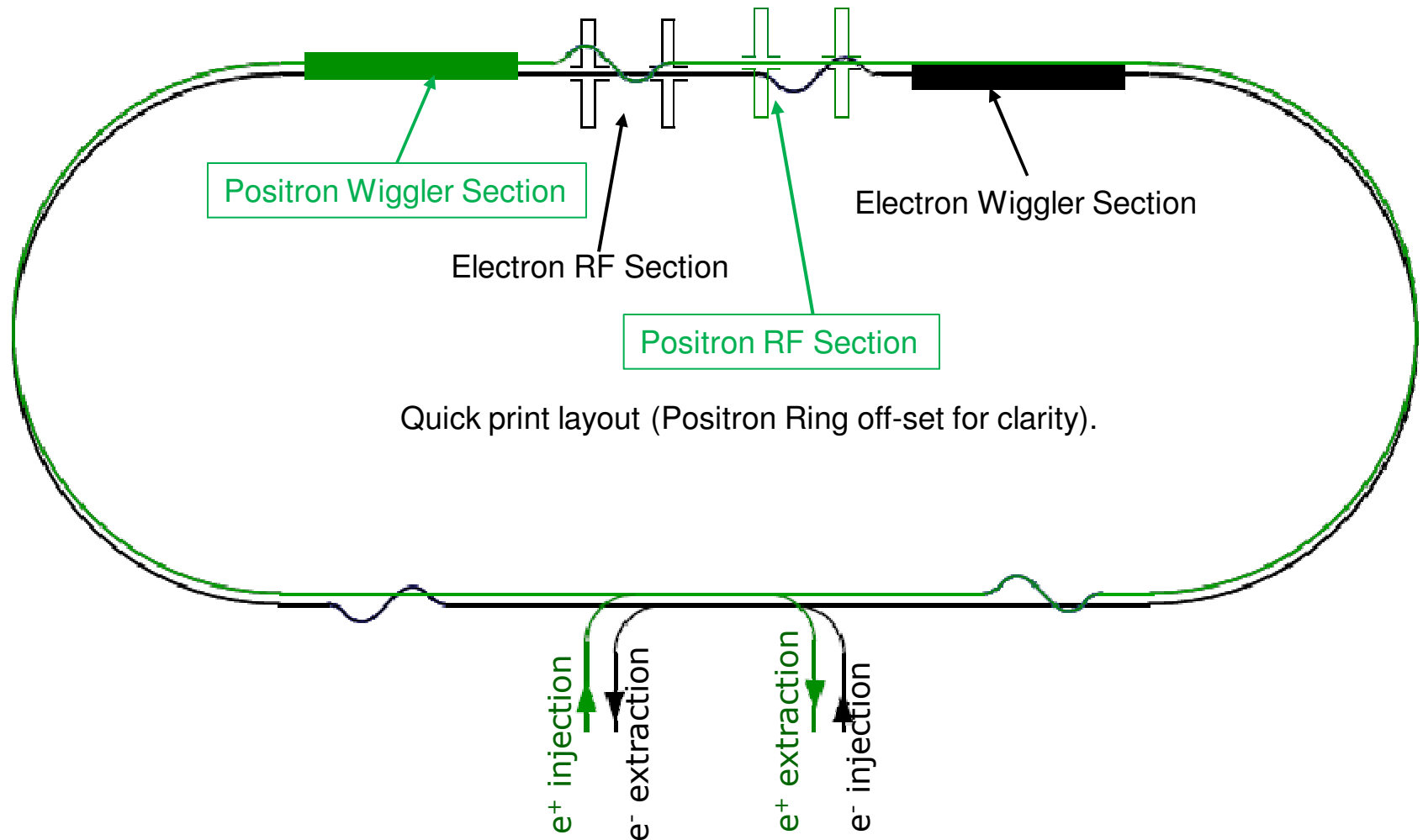
## Engineering Model

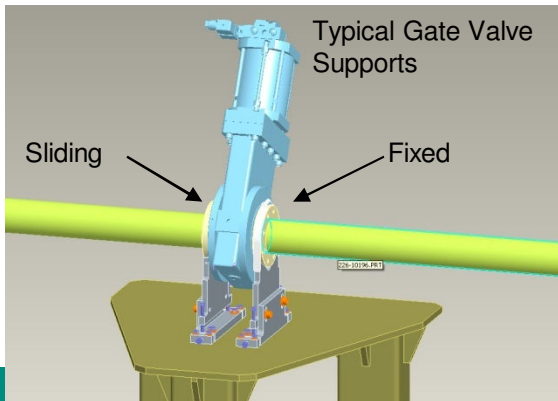
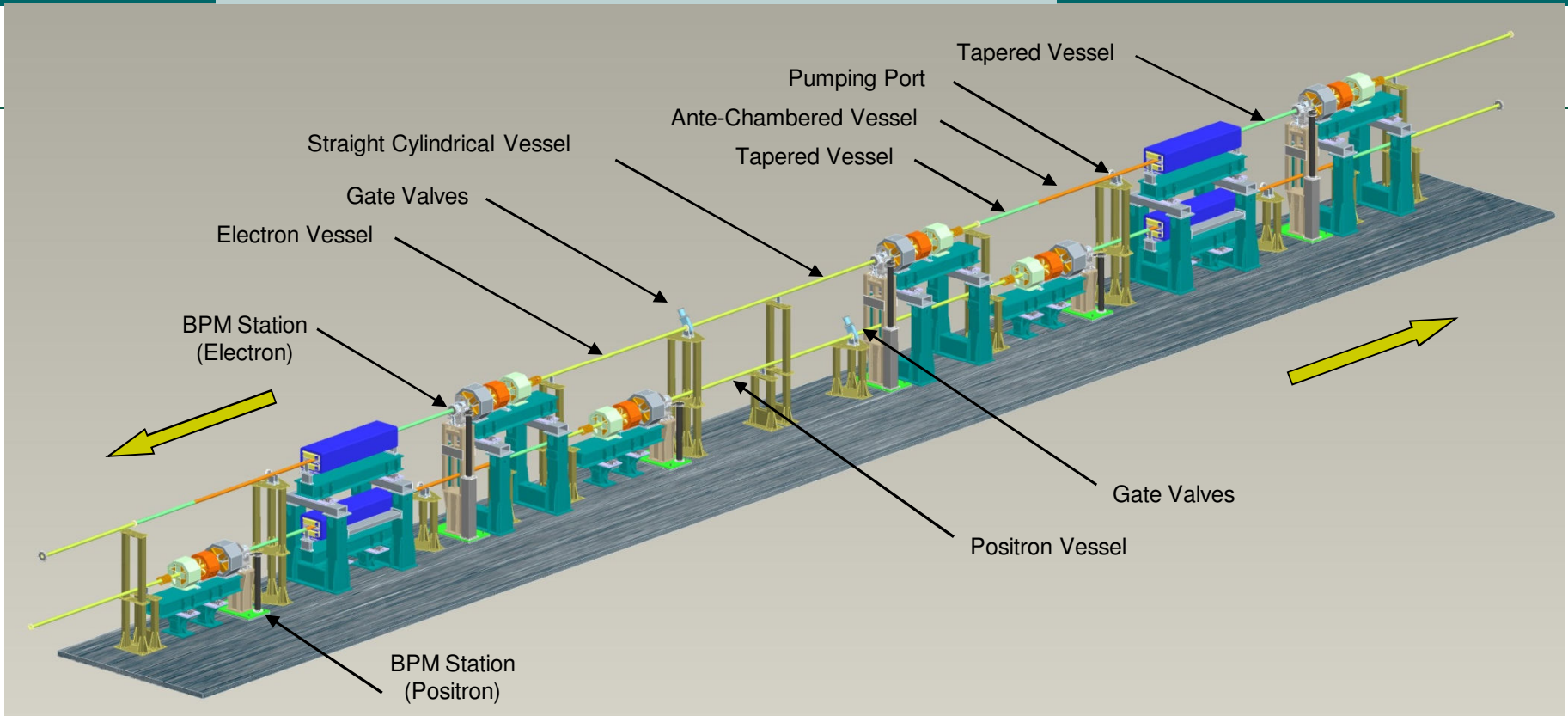
- Work by J. Lucas, N. Collomb and S. Postlethwaite (STFC Technology)
- Developing a CAD model for mechanical integration of vacuum system, BPMs, magnets and supports.



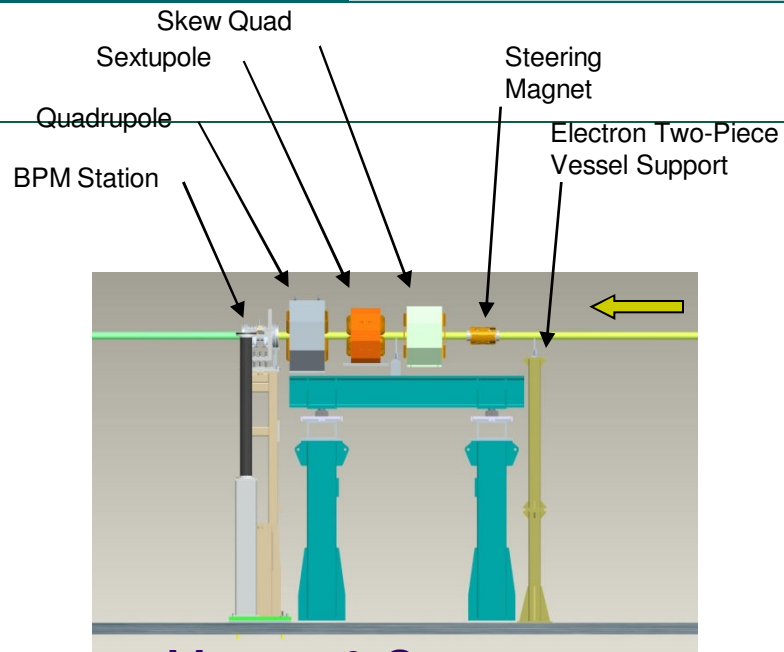
- Goals:
  - to demonstrate engineering feasibility of both the Electron & Positron Damping Ring Periodic Arc Cells;
  - to provide a basis for further design and beam dynamics studies and costing of vacuum, magnets, conventional facilities, etc.

# DC04 Overall Layout (simplified)

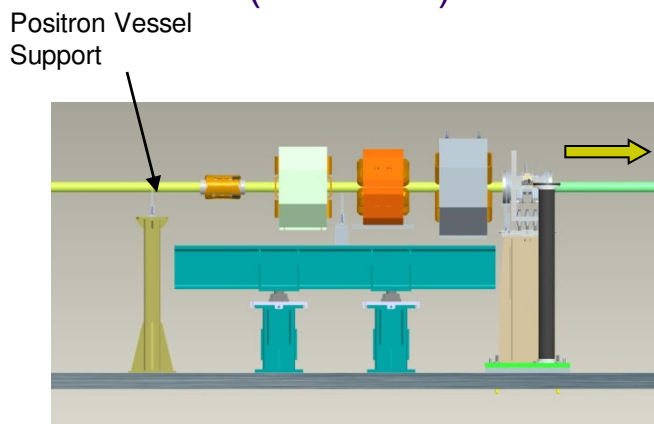




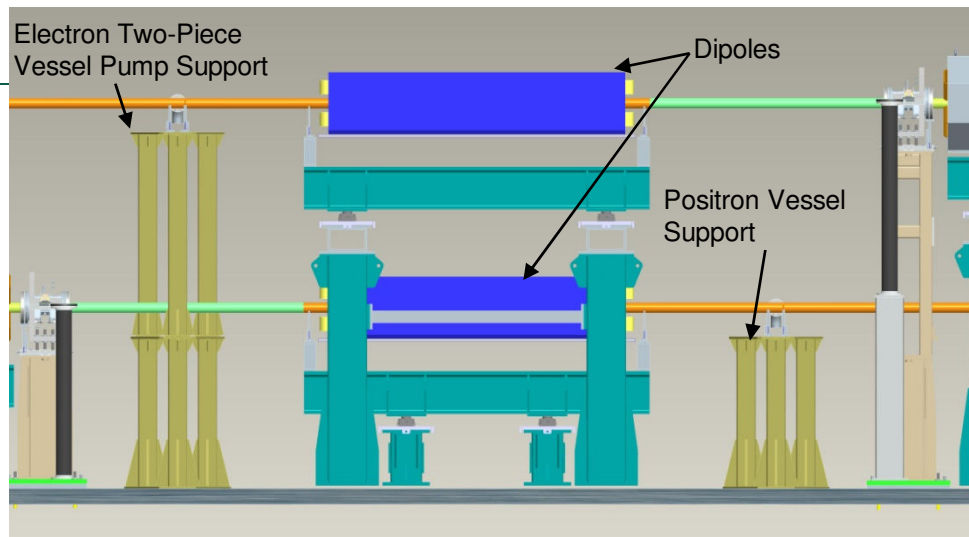
- Work has focused on developing the model for a Single Arc Cell (Linear)
- One Gate Valve per 5 Arc Cells
- Gate Valve supports consist of one fixed and one sliding
- Bellows allow for 4.5 mm/meter thermal expansion (NEG activation at 160-180 °C).



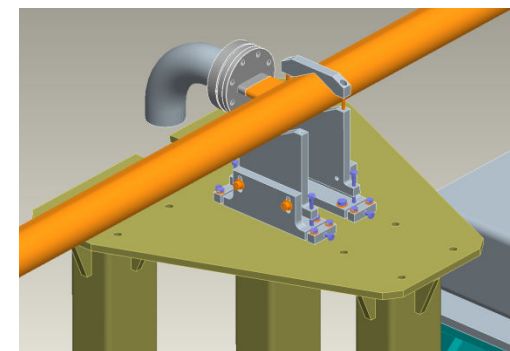
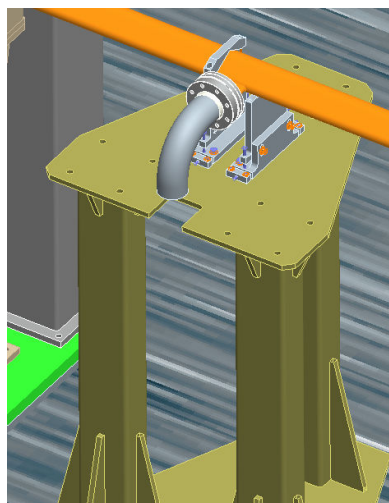
Magnet & Supports –  
(Electron)



Magnet & Supports



Dipoles & Supports



Vessel Pumping Supports

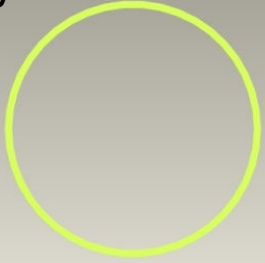
## Vacuum system: key features

- Vacuum chamber mostly consists of straight cylindrical tube.
  - Internal diameter 60 mm, wall thickness 2 mm.
- Antechamber and cooling provided in dipoles and a few meters downstream.
  - Intended to reduce build-up of electron cloud by reducing the number of photons in the beam chamber.
  - Dipole chamber will consist of extruded vessel with antechamber, welded to machined "taper" sections.
  - A pumping port is included in antechamber downstream of dipole.
- All vacuum chambers are NEG coated

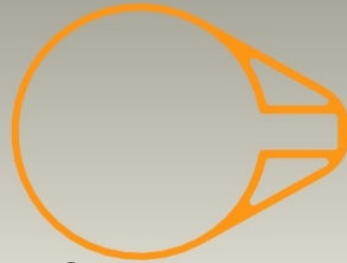


# Vacuum Vessel Profiles

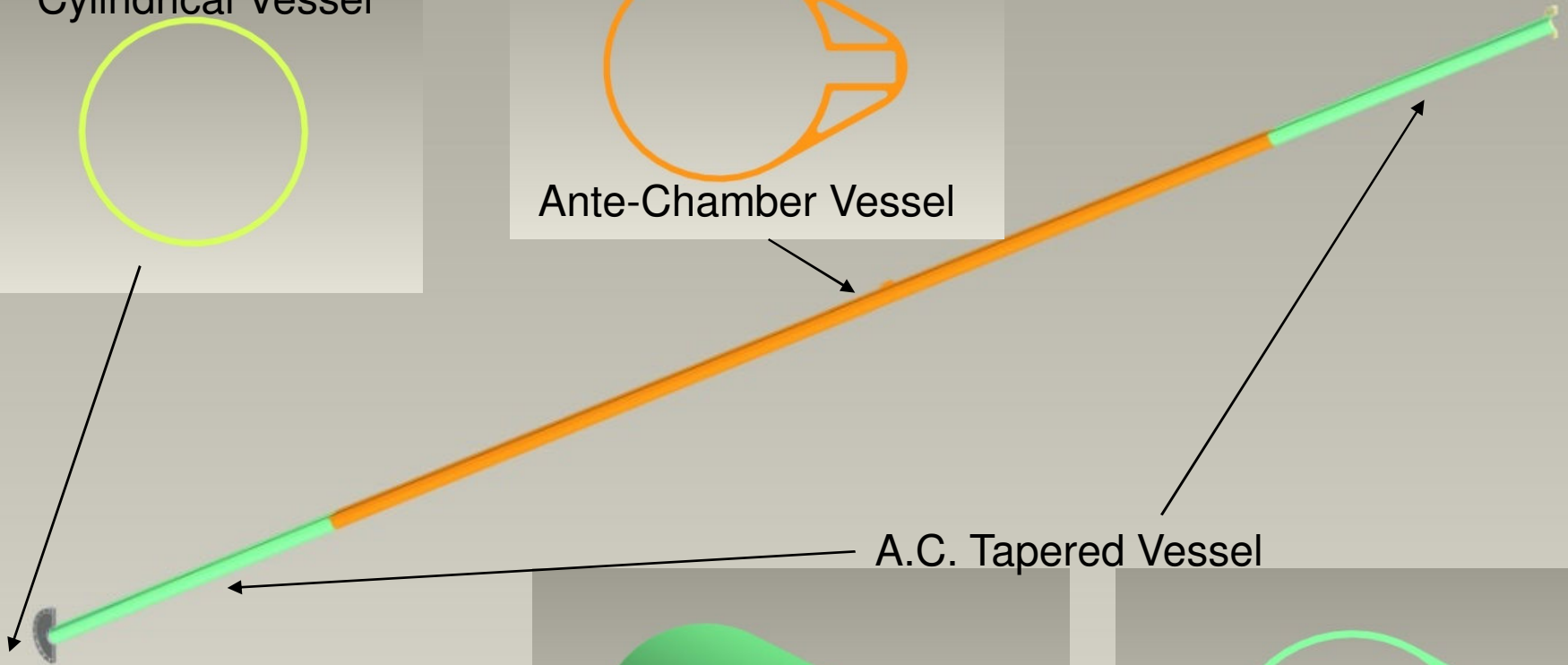
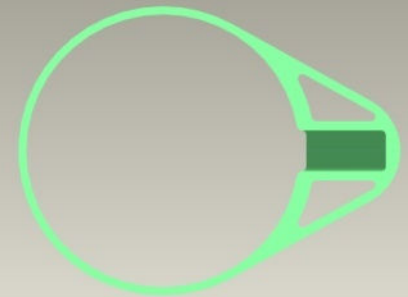
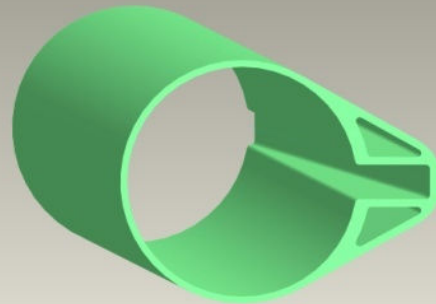
Cylindrical Vessel



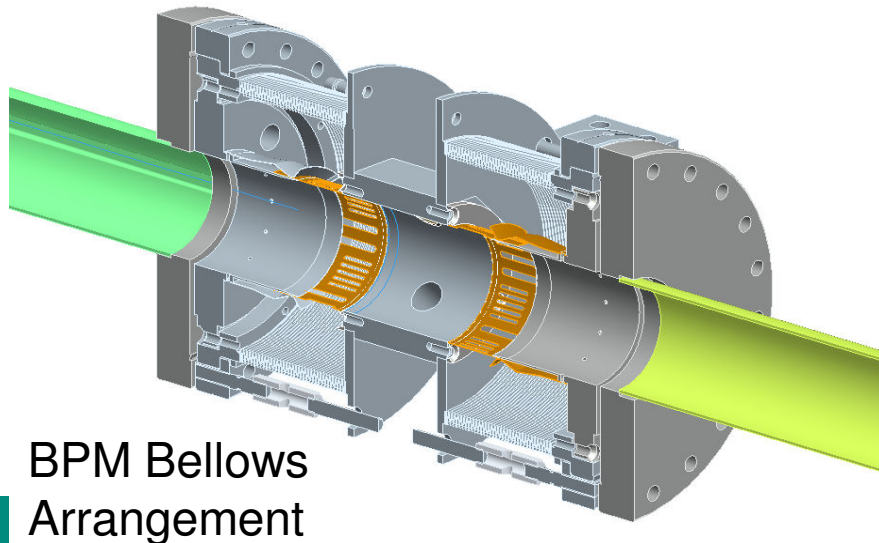
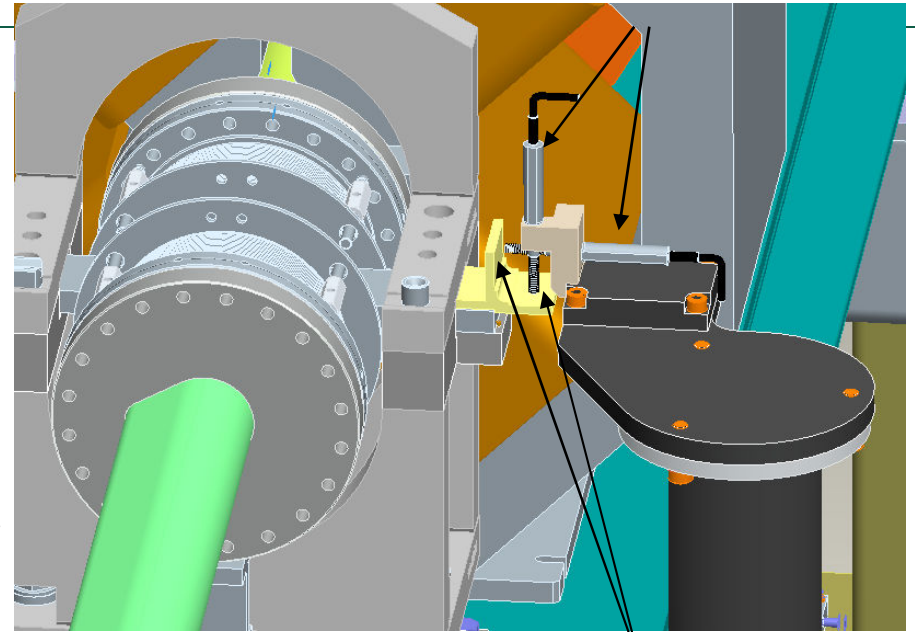
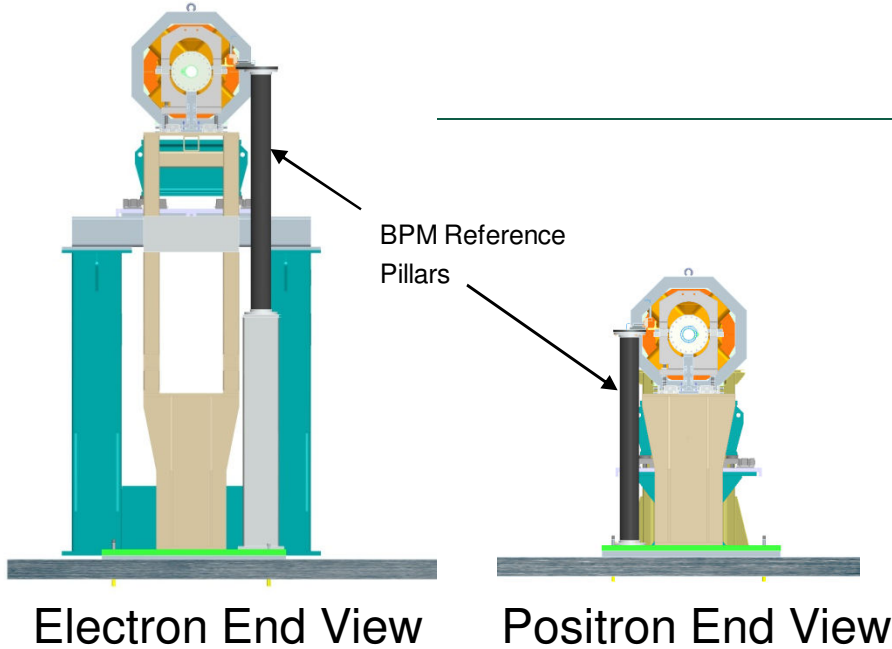
Ante-Chamber Vessel



A.C. Tapered Vessel



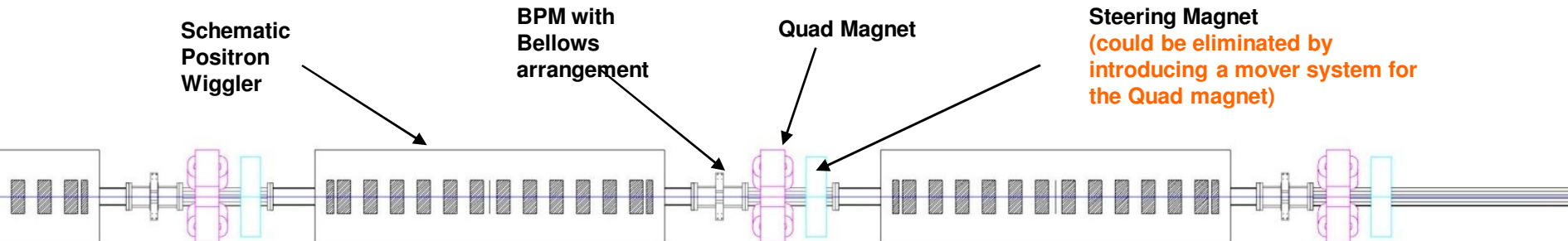
# Vacuum Vessel BPM Stations



## Position Encoders

- Fitted on all BPM Blocks
- Reference Pillar provides reference points for the beam orbit.
- Position Encoders monitor any motion of BPMs from thermal or mech effects

# DC04 Wiggler Section



Challenges in a wiggler section design:

- SR power absorption – up to ~40 kW per wiggler
  - Power dissipation calculation by K. Zolotarev (BINP)
- Minimising a number of SR photons hitting beam chamber inside a wiggler to provide low PEY
  - Antechamber and shadow
- Grooved top and bottom and TiN coating to provide low SEY
- Sufficient pimping (NEG strips + SIPs)
- Impedance calculation by M. Korostelev (CI and Liverpool University)

Big thank to Cornell and LBNL for their information on the CESR-TA wiggler design.



# ILC Damping Ring – Wiggler Section

88 Section repetitions  
for 6.4km circumference  
Damping Ring

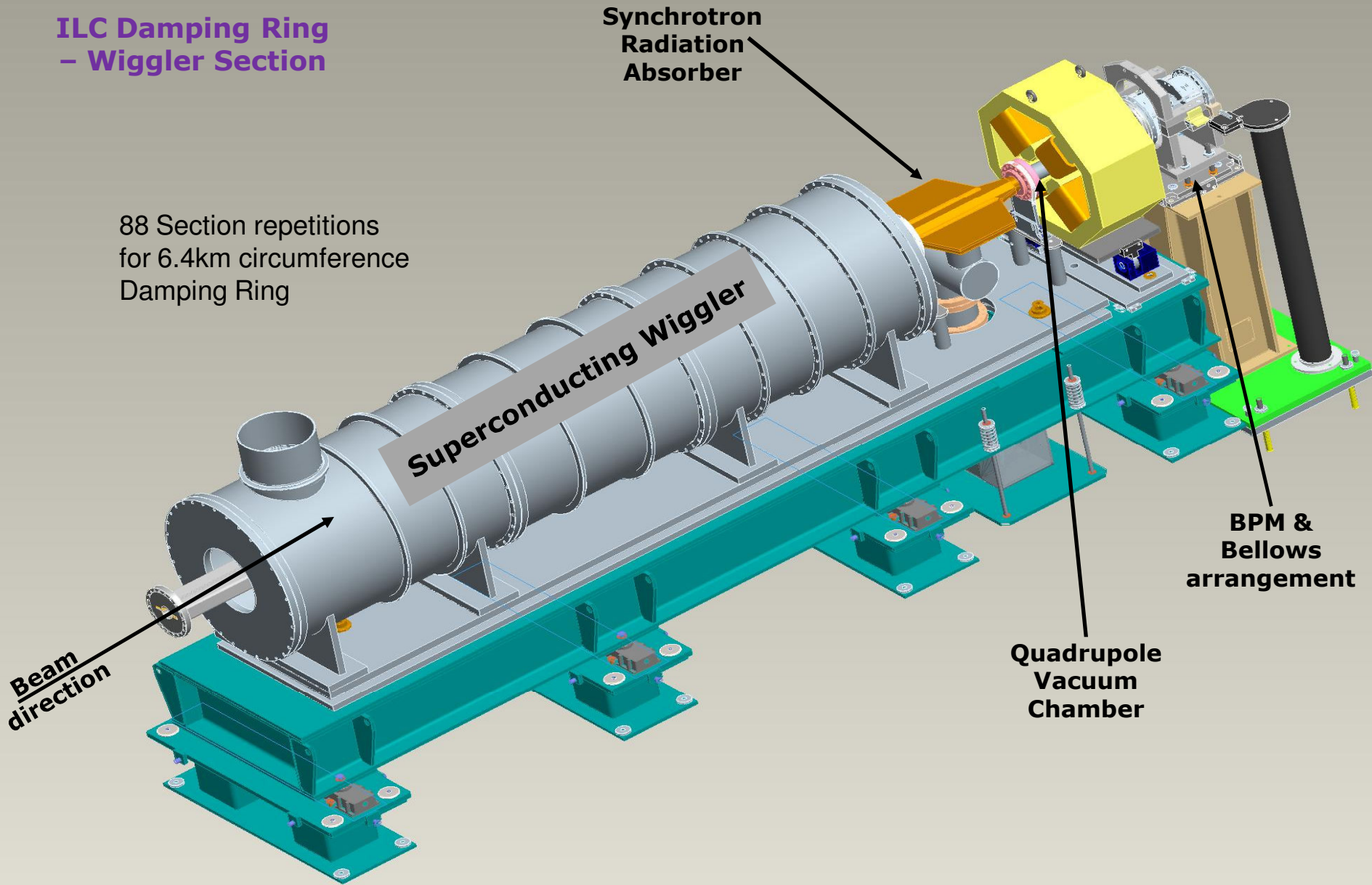
Synchrotron  
Radiation  
Absorber

Superconducting Wiggler

BPM &  
Bellows  
arrangement

Quadrupole  
Vacuum  
Chamber

Beam  
direction



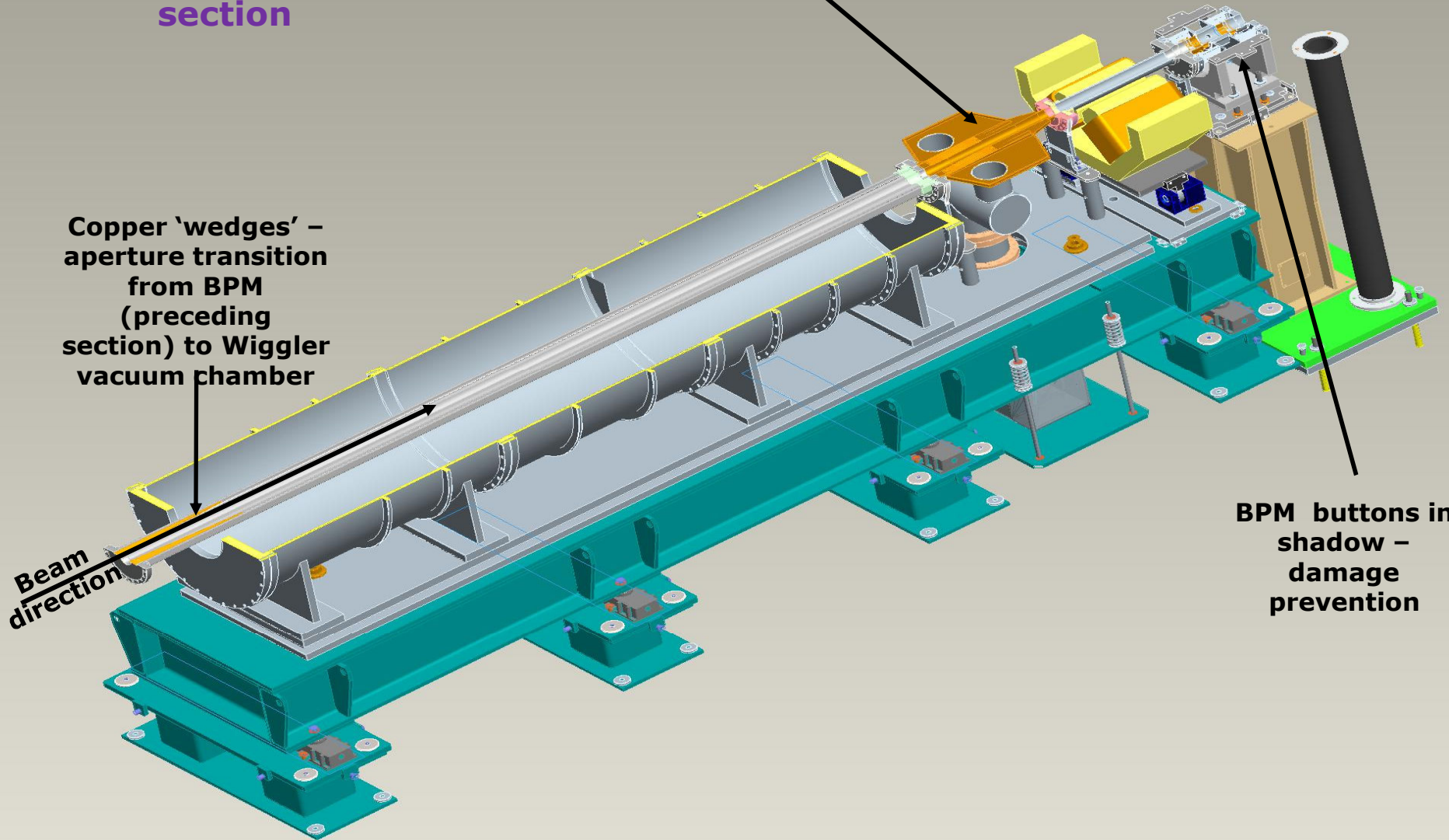
# ILC Damping Ring - Wiggler Section - Vacuum Chamber cross- section

High Power  
Synchrotron  
Radiation  
Absorber

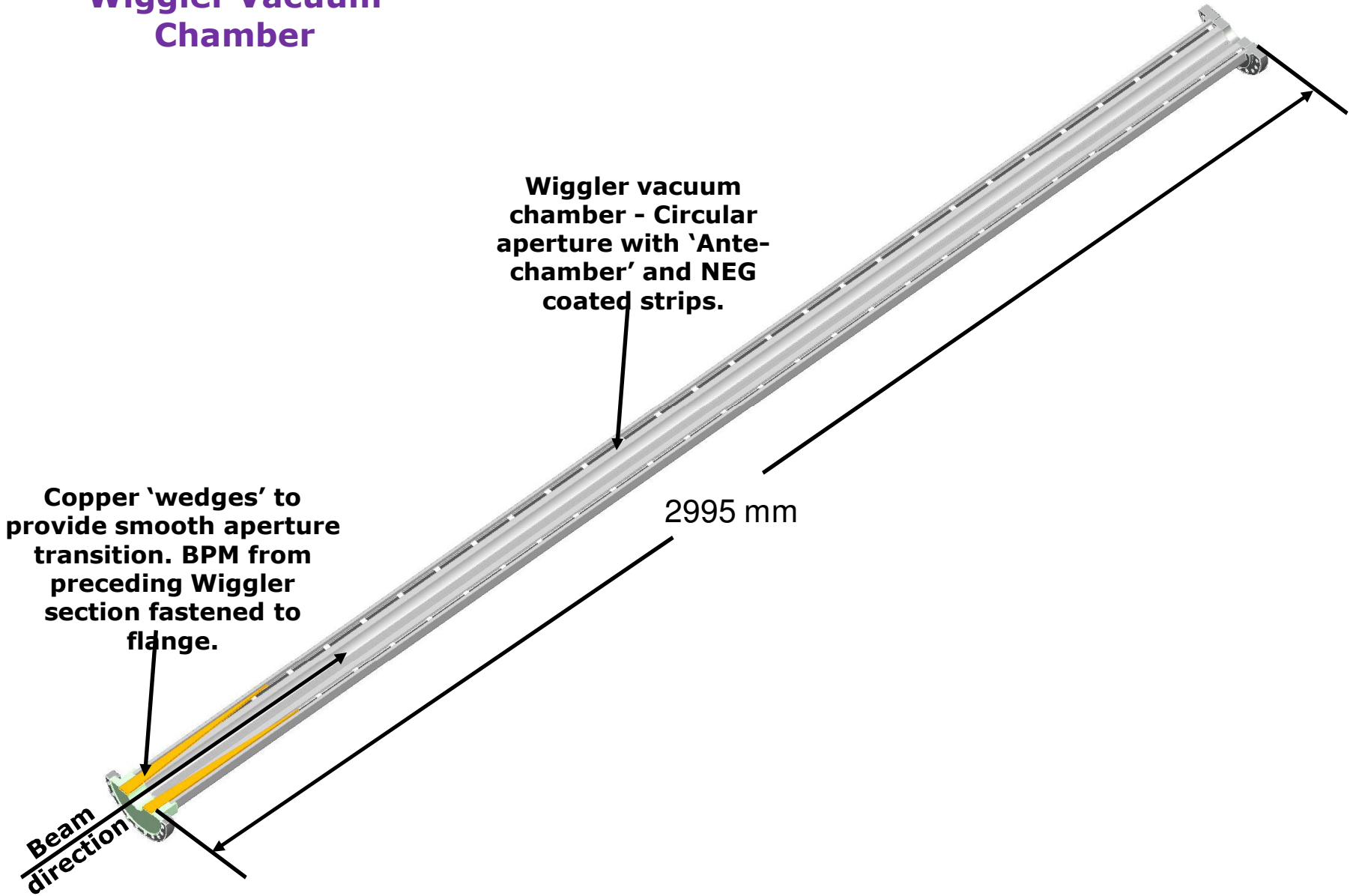
Copper 'wedges' –  
aperture transition  
from BPM  
(preceding  
section) to Wiggler  
vacuum chamber

Beam  
direction

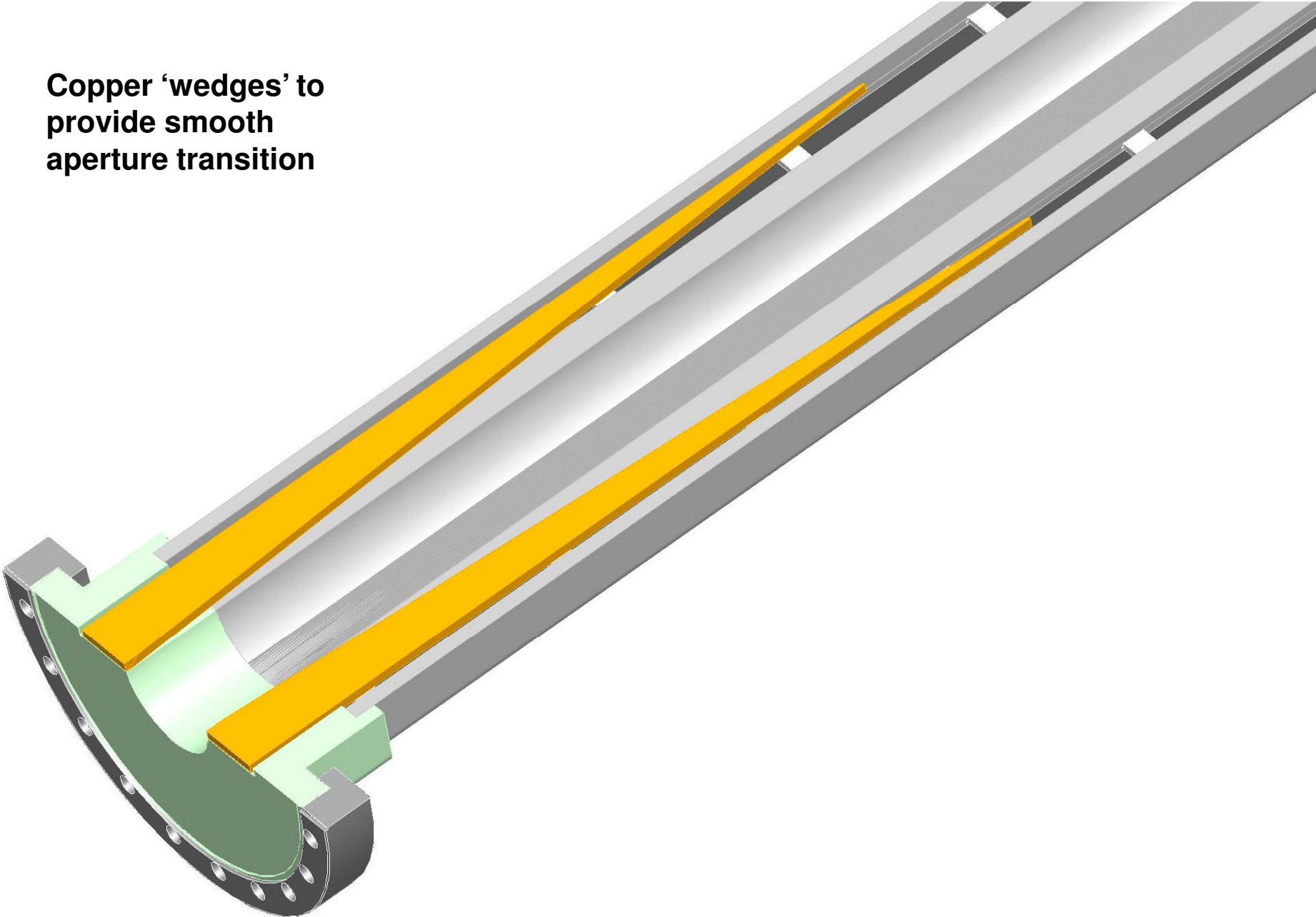
BPM buttons in  
shadow –  
damage  
prevention



# ILC Damping Ring – Wiggler Vacuum Chamber

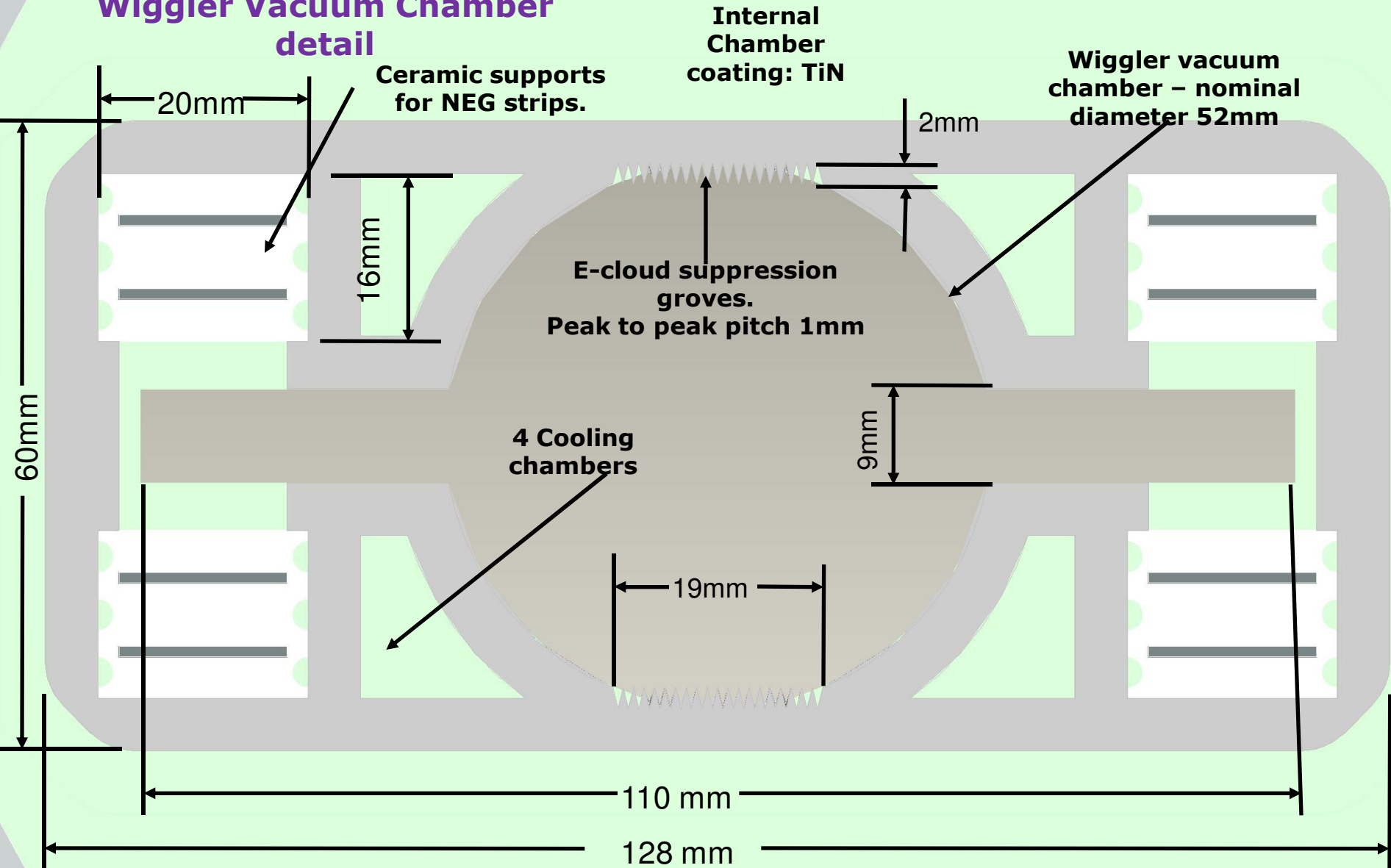


**Copper 'wedges' to  
provide smooth  
aperture transition**





# ILC Damping Ring – Wiggler Vacuum Chamber detail



# ILC Damping Ring – Wiggler Vacuum Chamber detail

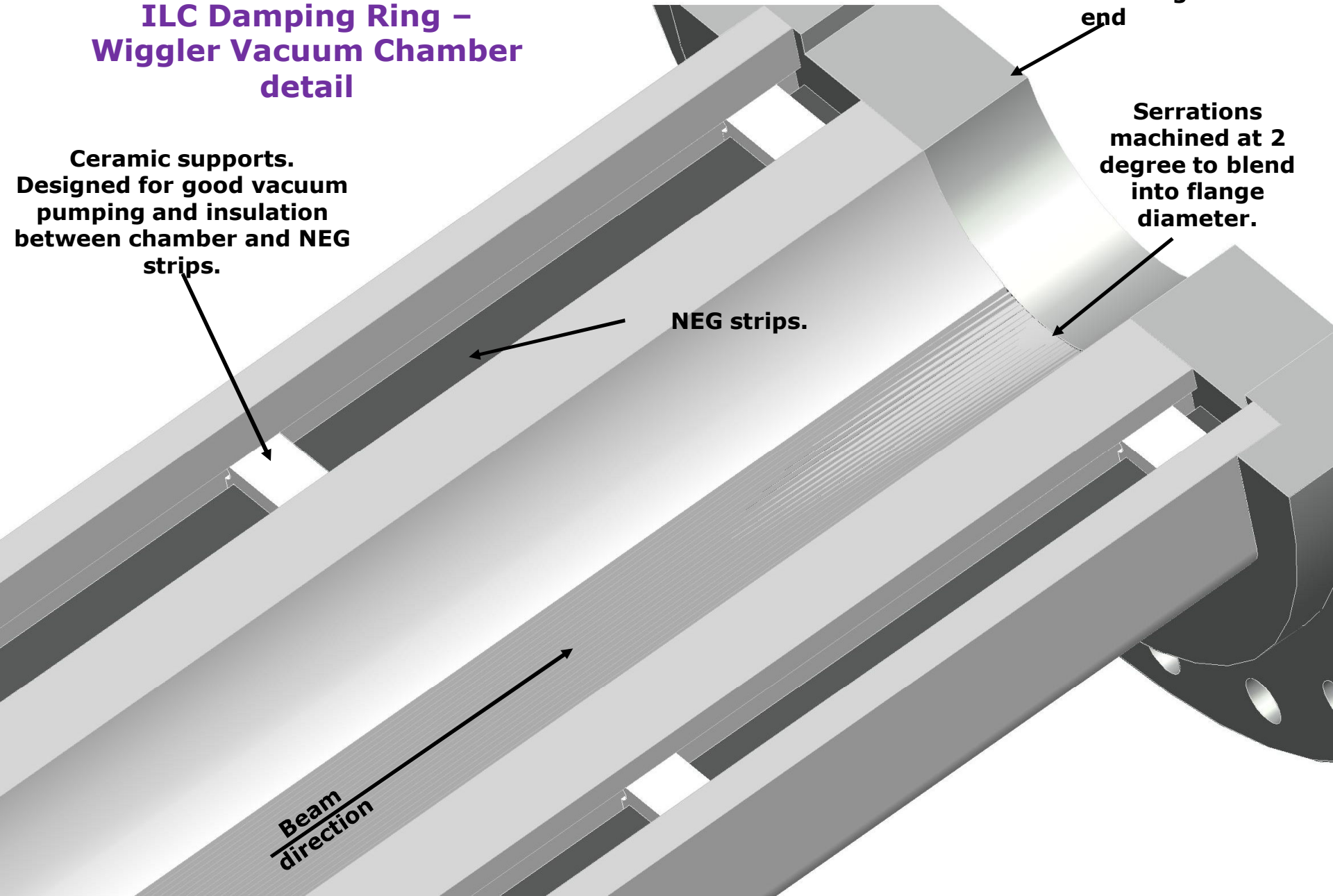
Absorber flange  
end

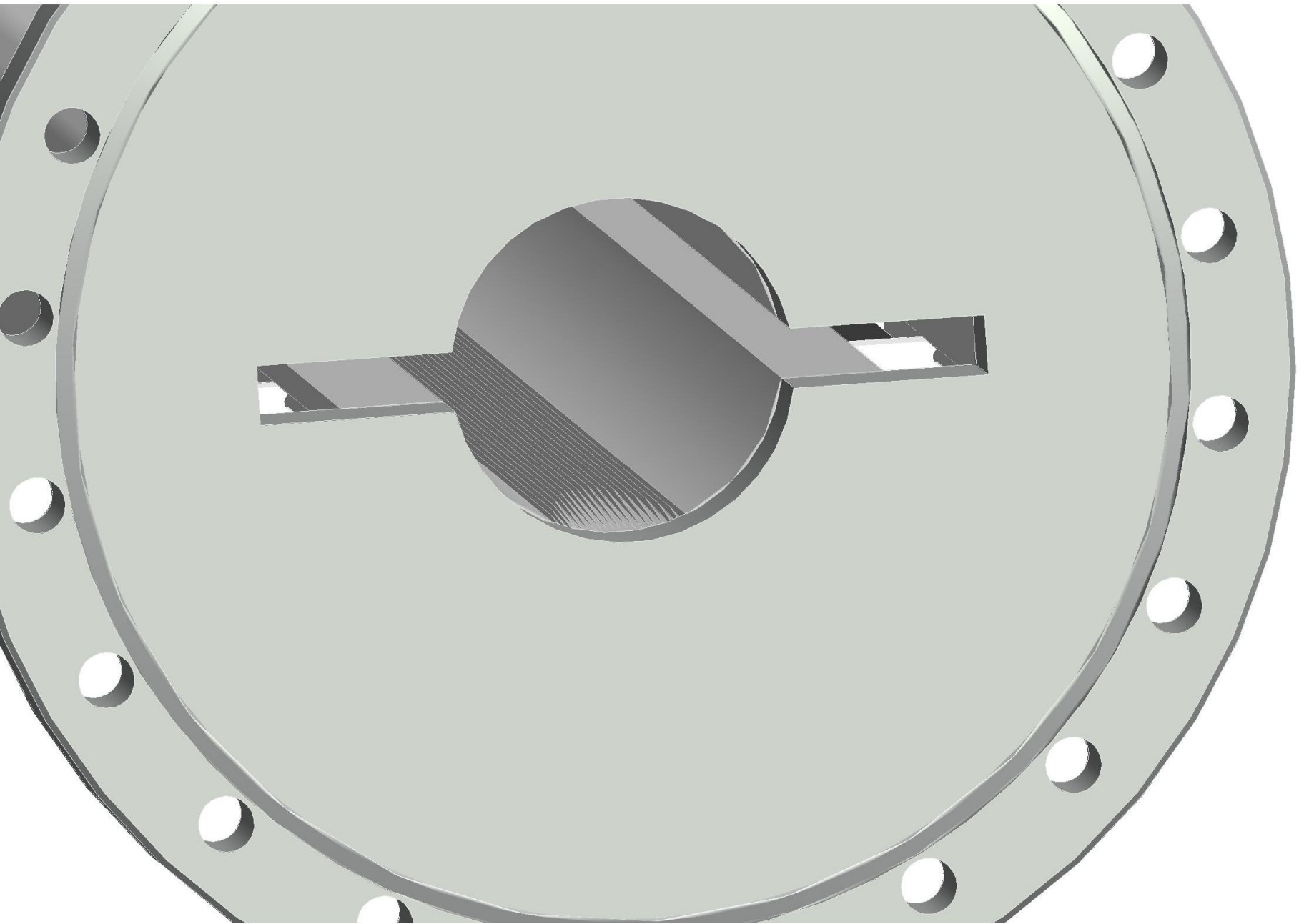
Serrations  
machined at 2  
degree to blend  
into flange  
diameter.

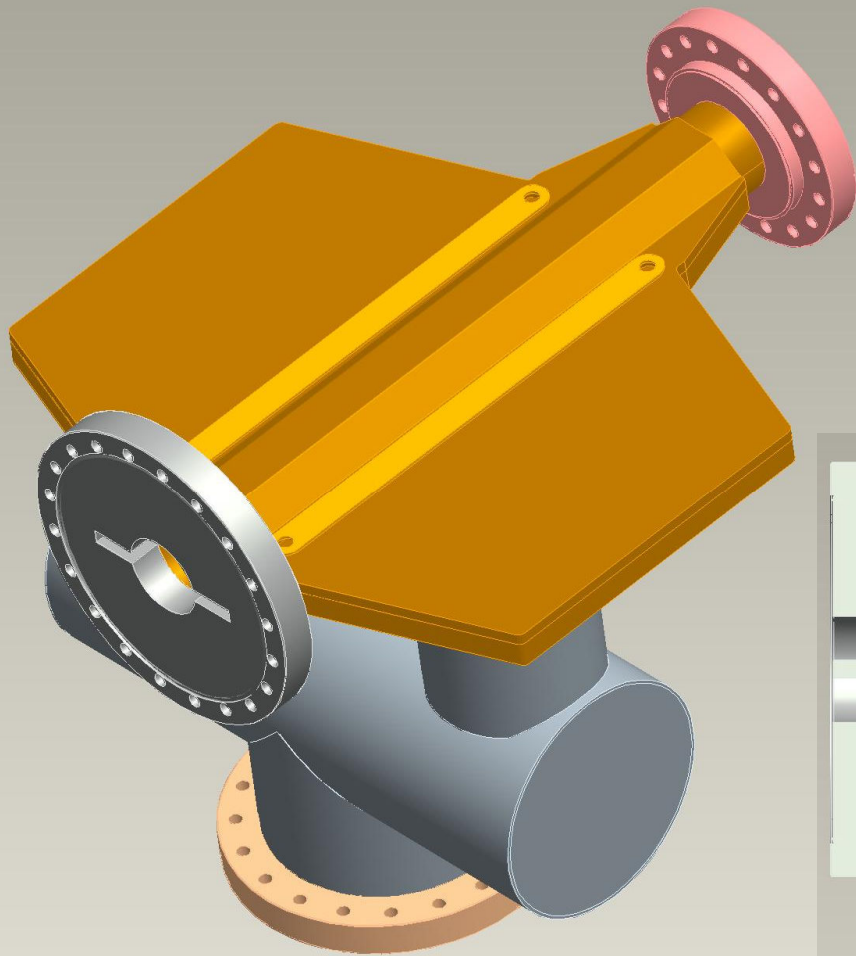
NEG strips.

Ceramic supports.  
Designed for good vacuum  
pumping and insulation  
between chamber and NEG  
strips.

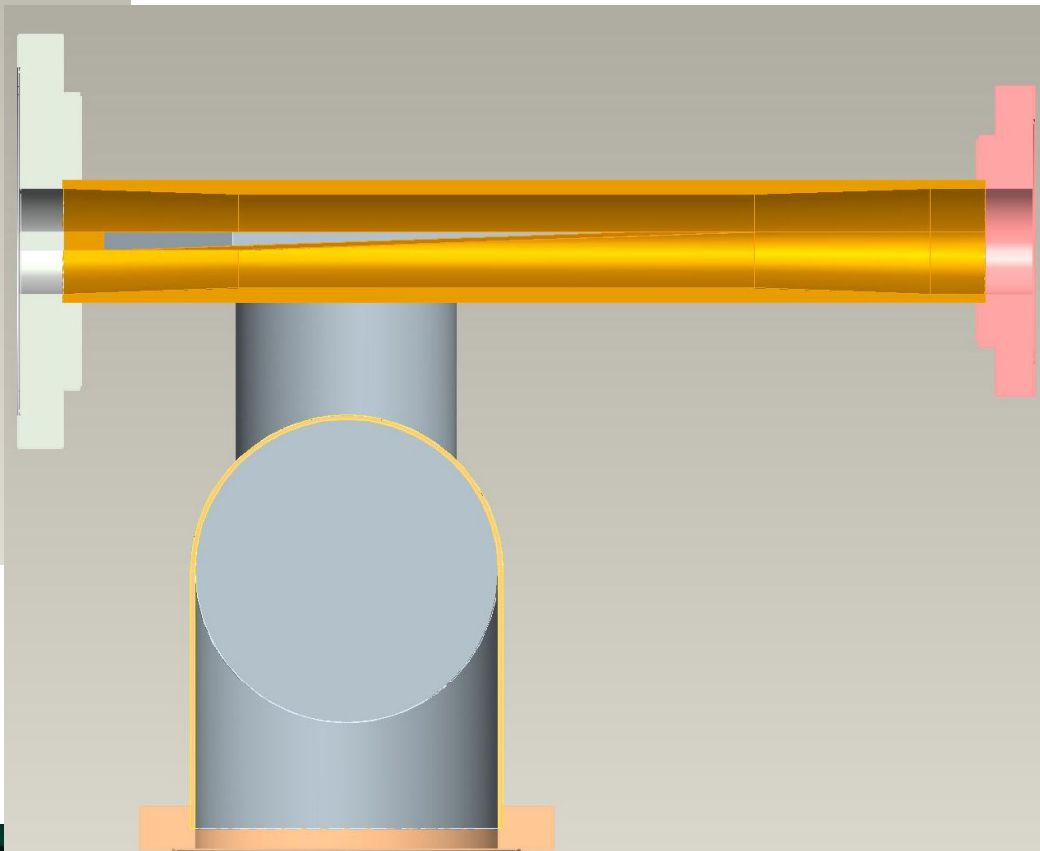
Beam  
direction





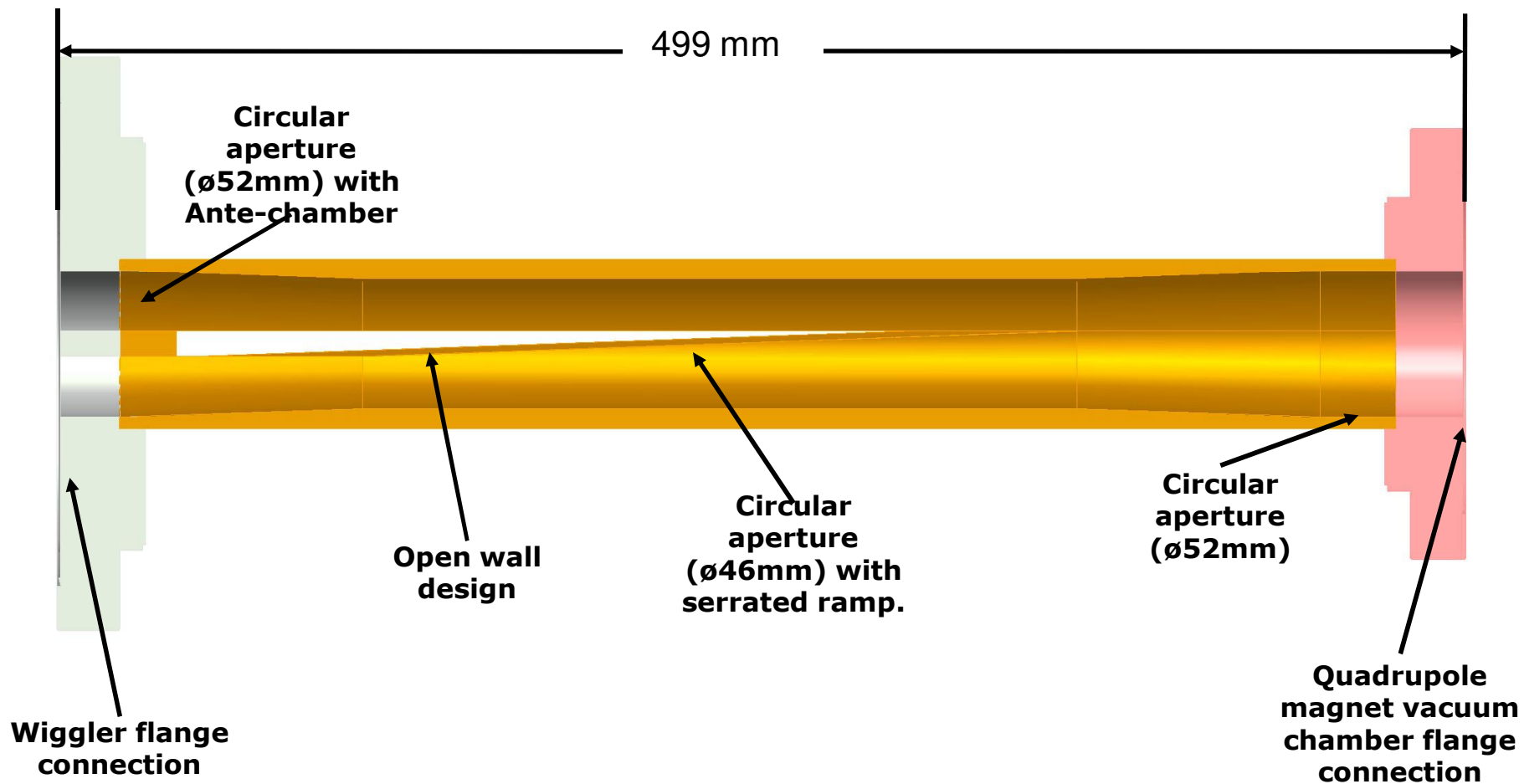


## ILC Damping Ring – SR Absorber detail



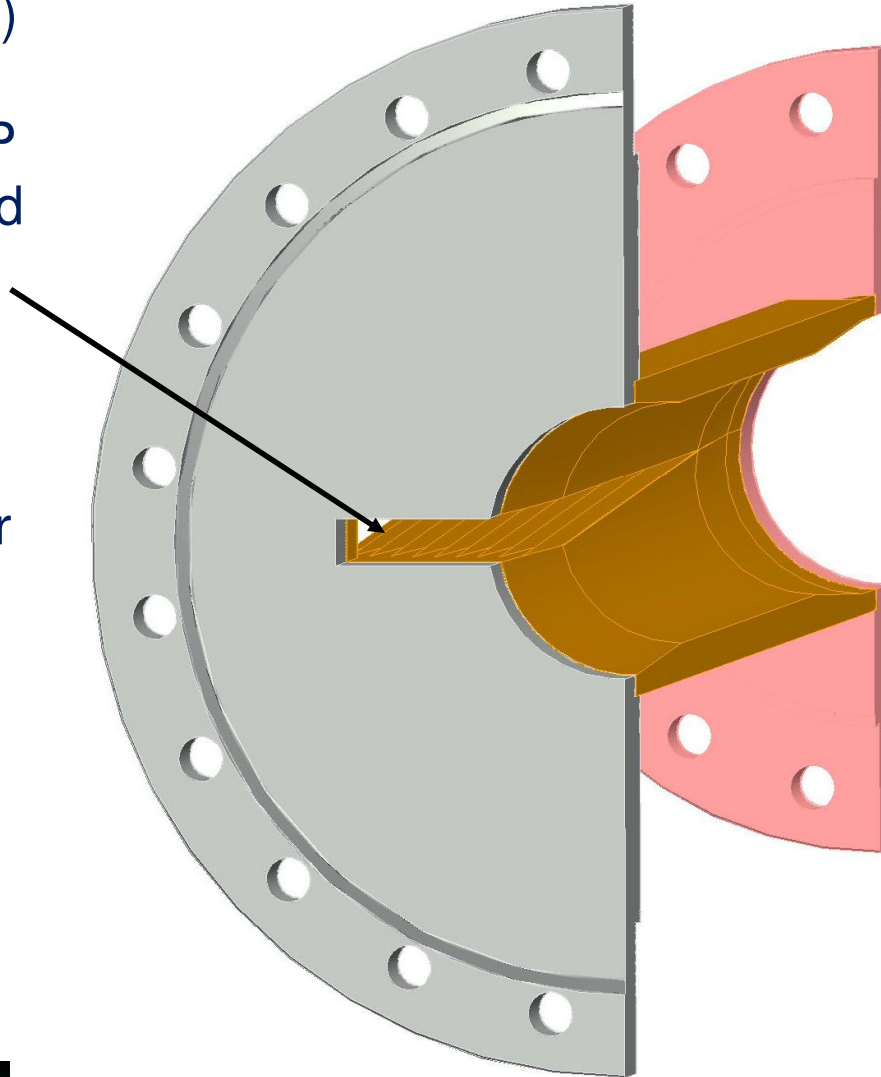


## ILC Damping Ring – SR Absorber detail



The ramped (or saw tooth) absorber geometry was originally invented at BINP for SR absorbers designed for Siberia-2 LS (Russia)

This geometry was also used for a crotch absorber in the Diamond LS (UK)

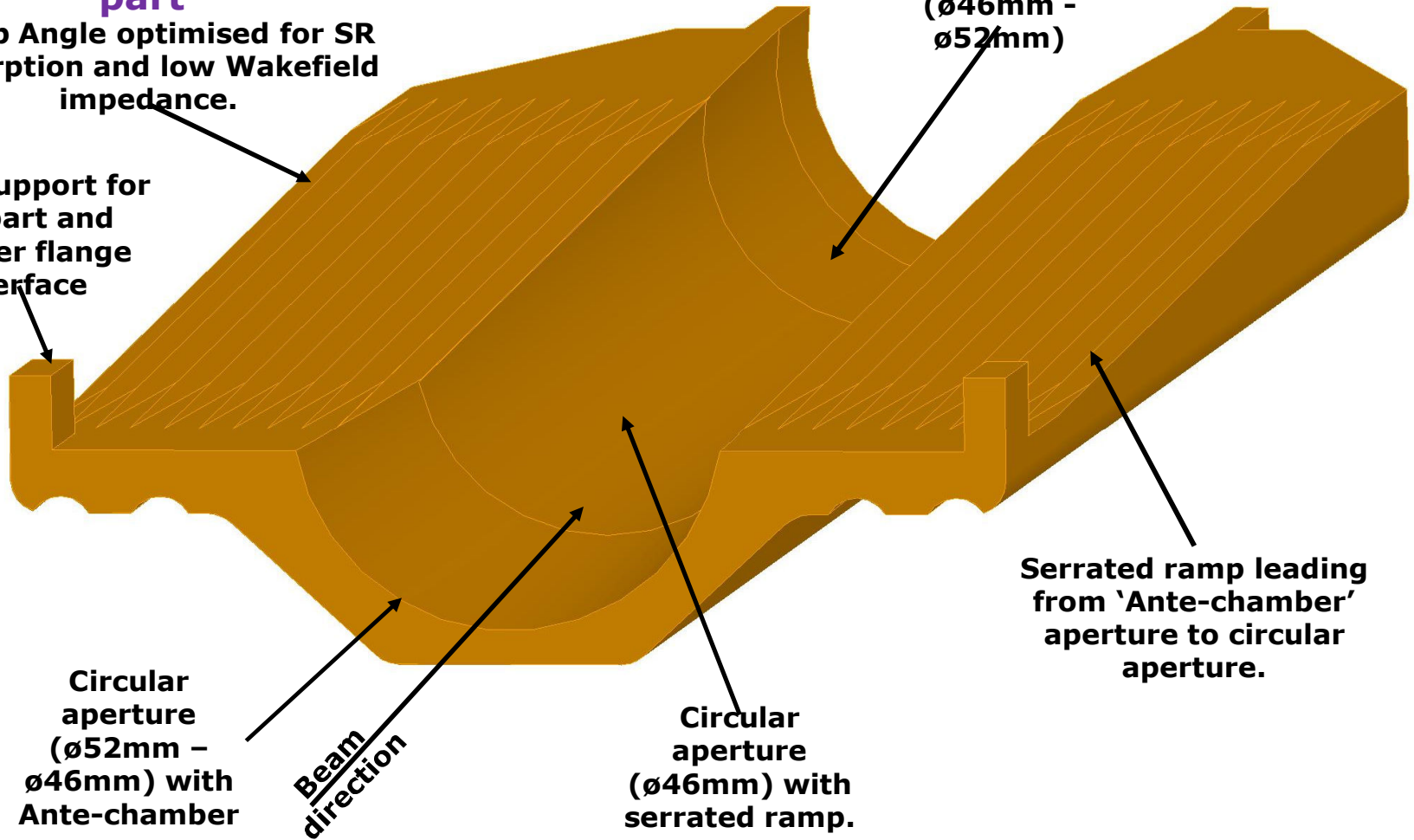


# ILC Damping Ring – SR Absorber detail Bottom manufactured part

Ramp Angle optimised for SR absorption and low Wakefield impedance.

Pillar support for top part and Wiggler flange interface

Circular aperture (ø46mm - ø52mm)



Circular aperture (ø52mm - ø46mm) with Ante-chamber

Beam direction

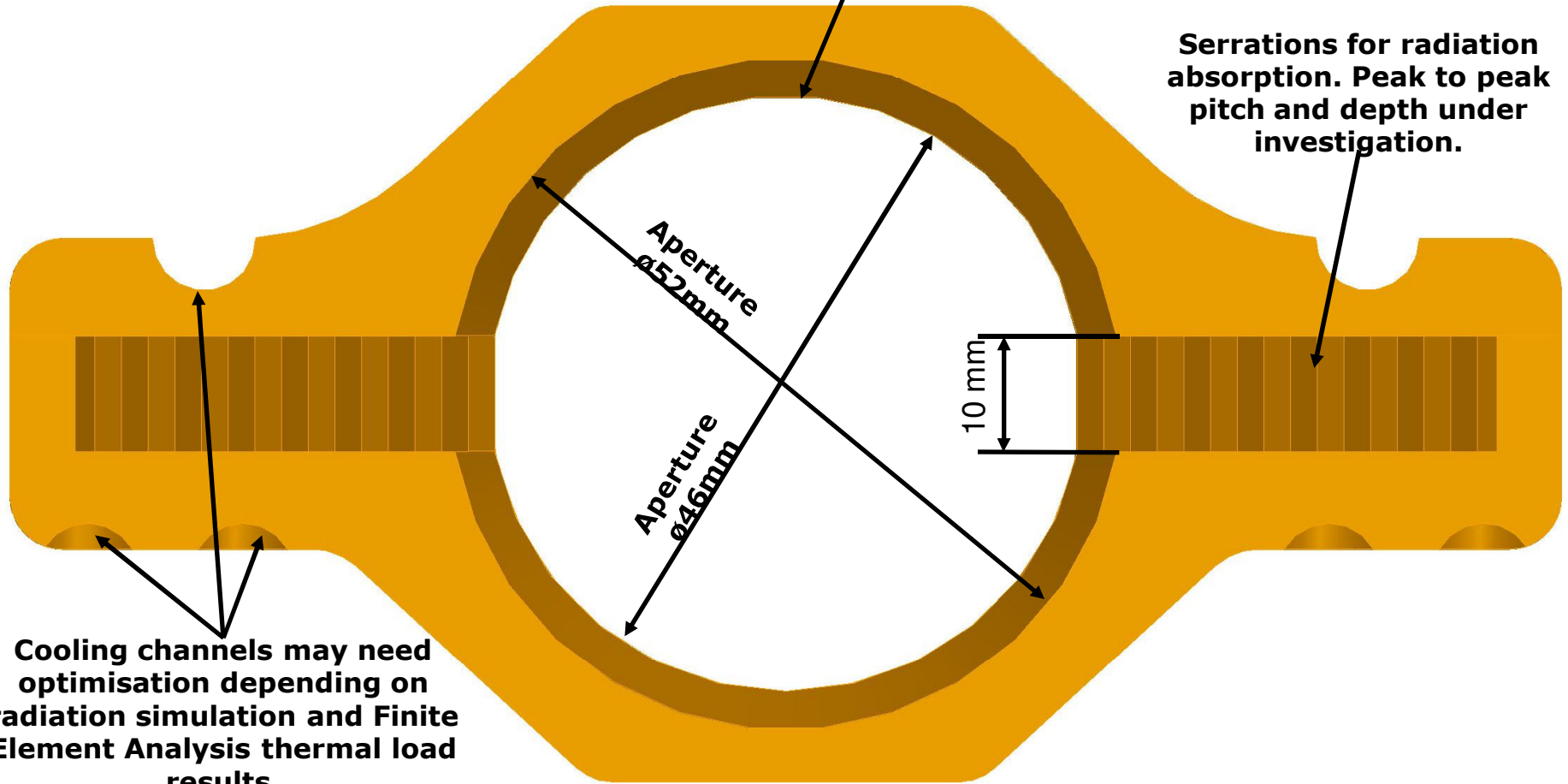
Circular aperture (ø46mm) with serrated ramp.

Serrated ramp leading from 'Ante-chamber' aperture to circular aperture.

## ILC Damping Ring – SR Absorber detail

Smaller aperture  
provides shadow for  
BPM

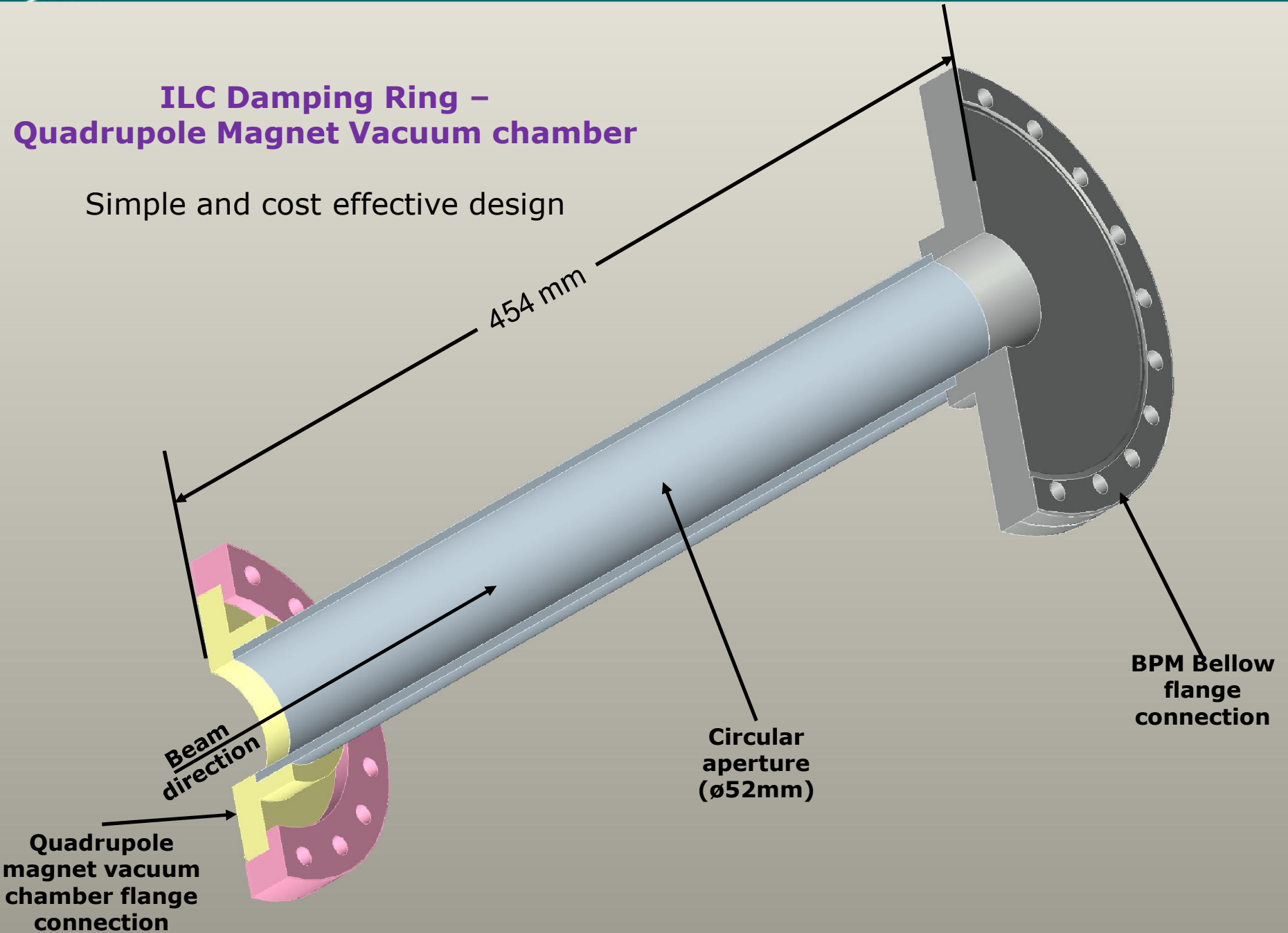
Serrations for radiation  
absorption. Peak to peak  
pitch and depth under  
investigation.



Cooling channels may need  
optimisation depending on  
radiation simulation and Finite  
Element Analysis thermal load  
results.

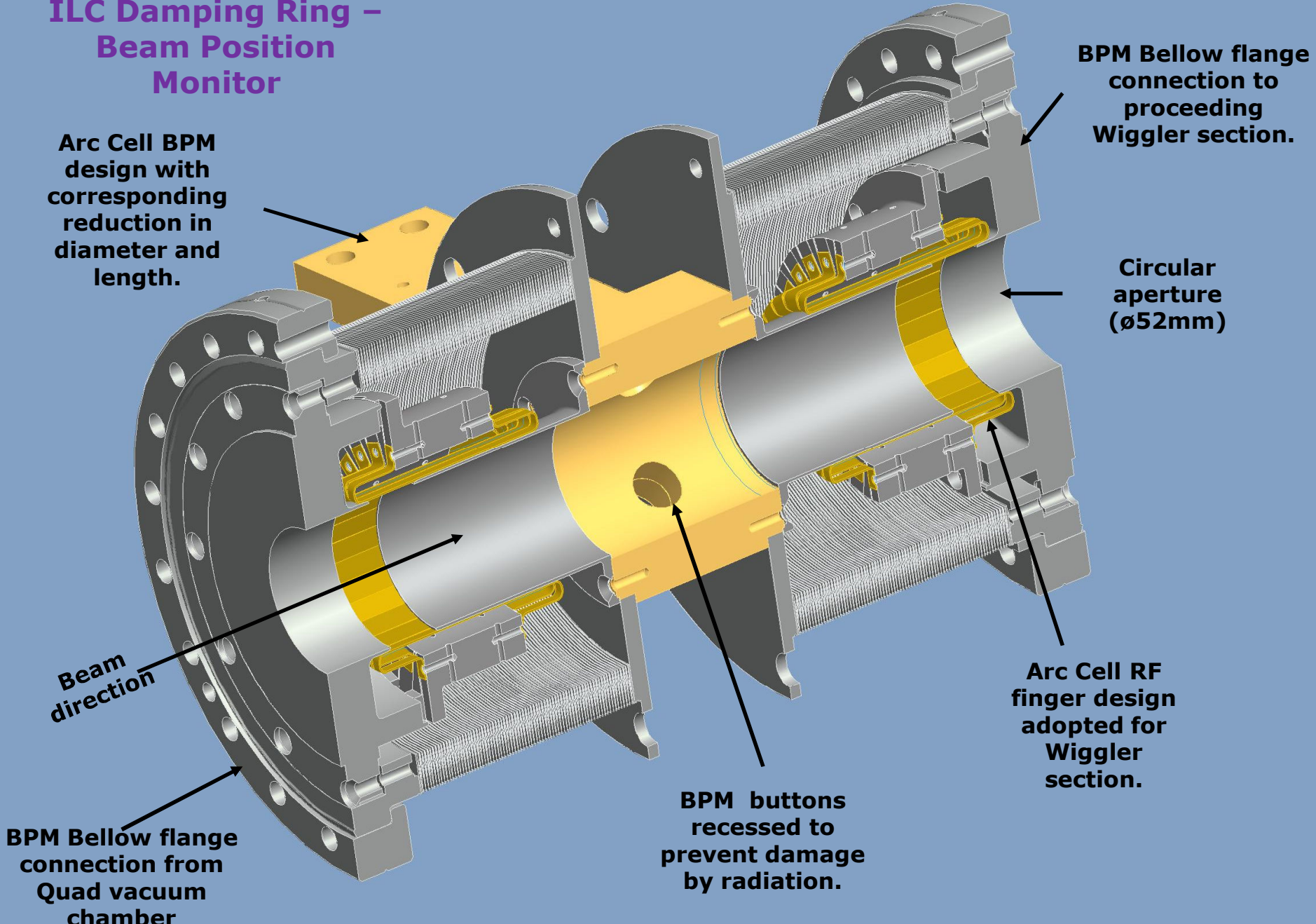
# ILC Damping Ring – Quadrupole Magnet Vacuum chamber

Simple and cost effective design





# ILC Damping Ring – Beam Position Monitor



## Conclusions

- Mechanical design of ILC DR vacuum vessel includes requirements from
  - Impedance, e-cloud, power absorption and vacuum models
  - Low cost
- Drawing of vacuum vessel of ILC DR are available to be used for the next run of modelling.
  - Impedance and wake field calculation
  - e-cloud modelling
  - Vacuum system design
- Although the design is made for 6.4-km ring, most of the components could be used for 3.2-km rings models.